

➔ WS-8800 Fully automatic(robotic transfer) 4 point probe system for silicon wafer



Selling Points

- Measurement of resistivity, thickness, conductivity(P/N) and temperature
- Tester self-test function, wide measuring range
- Correction function for silicon resistivity(thickness,temperature, measurement position)
- Number of cassette station can be changed by customers request
- Host (CIM) communication and SMIF or FOUP compatible

Details

Applications

Semiconductor materials, Solar-cell materials (Silicon, Polysilicon, SiC etc)
Others (*Please contact us for details)

Sample sizes

3 ~ 8 inch (or 12 inch)

Measuring range

[R] 100 μ ~1M Ω ·cm

[RS] 1m~10M Ω /sq

